

**IN THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application.

1-50. (Canceled)

51. (Previously Presented) A camera comprising a main body and a display monitor attached to the main body, said display monitor comprising:

a light emitting layer sandwiched between a cathode and an anode; and

a passivation film formed on said anode,

wherein a halogen element is contained in a portion of said light emitting layer, and

wherein said portion is in contact with said anode.

52-103 (Canceled)

104. (New) A method of manufacturing an EL display device comprising the steps of:

forming a cathode;

forming an organic layer comprising a light emitting material over the cathode;

forming an anode over the organic layer; and

introducing a halogen element into a portion of the organic layer through at least the anode so that the portion of the organic layer functions as a hole transport layer,

wherein the portion of the organic layer is in contact with the anode.

105. (New) The method according to claim 104 further comprising a step of forming a passivation film on the anode wherein the halogen element is introduced through the passivation film.

106. (New) The method according to claim 104, wherein the halogen element is introduced in such a manner that a concentration of the halogen element is highest in a vicinity of an interface between the anode and the organic layer.

107. (New) The method according to claim 105 wherein the passivation film comprises an insulating film which contains silicon.

108. (New) A method of manufacturing an EL display device comprising the steps of:  
forming a cathode;  
forming an organic layer comprising a light emitting material over the cathode;  
forming an anode over the organic layer;  
forming an insulating film over the anode;  
introducing a halogen element into a portion of the organic layer through at least the insulating film so that the portion of the organic layer functions as a hole transport layer,  
wherein the portion of the organic layer is in contact with the anode.

109. (New) The method according to claim 108, wherein the halogen element is introduced in such a manner that a concentration of the halogen element is highest in a vicinity of an interface between the anode and the organic layer.

110. (New) The method according to claim 108 wherein the insulating film comprises silicon.

111. (New) A method of manufacturing an EL display device comprising the steps of:  
forming a cathode;  
forming an organic layer comprising a light emitting material over the cathode;  
forming an anode over the organic layer;  
introducing an alkali metal element into a portion of the organic layer through at least the anode so that the portion of the organic layer functions as an electron transport layer,  
wherein the portion of the organic layer is in contact with the cathode.

112. (New) The method according to claim 111 further comprising a step of forming a passivation film on the anode wherein the alkali metal element is introduced through the passivation film.

113. (New) The method according to claim 111, wherein the alkali metal element is introduced in such a manner that a concentration of the alkali metal element is highest in a vicinity of an interface between the cathode and the organic layer.

114. (New) The method according to claim 112 wherein the passivation film comprises an insulating film which contains silicon.

115. (New) A method of manufacturing an EL display device comprising the steps of:

forming a cathode;  
forming an organic layer comprising a light emitting material over the cathode;  
forming an anode over the organic layer;  
introducing an alkaline earth metal element into a portion of the organic layer through at least the anode so that the portion of the organic layer functions as an electron transport layer, wherein the portion of the organic layer is in contact with the cathode.

116. (New) The method according to claim 115 further comprising a step of forming a passivation film on the anode wherein the alkaline earth metal element is introduced through the passivation film.

117. (New) The method according to claim 115, wherein the alkaline earth metal element is introduced in such a manner that a concentration of the alkaline earth metal element is highest in a vicinity of an interface between the cathode and the organic layer.

118. (New) The method according to claim 116 wherein the passivation film comprises an insulating film which contains silicon.